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APPLICANTS

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**** CONTINUING DATA ******* *K-cc*

This application is a CON of 09/898,194 07/02/2001 PAT 6,673,721

**** FOREIGN APPLICATIONS ******* *none K-cc*

IF REQUIRED, FOREIGN FILING LICENSE GRANTED
**** 12/08/2003**

Foreign Priority claimed <input type="checkbox"/> yes <input checked="" type="checkbox"/> no 35 USC 119 (a-d) conditions met <input type="checkbox"/> yes <input checked="" type="checkbox"/> no <input type="checkbox"/> Met after Allowance Verified and Acknowledged	STATE OR COUNTRY CA	SHEETS DRAWING 2	TOTAL CLAIMS 5	INDEPENDENT CLAIMS 3
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ADDRESS
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TITLE
 Process for removal of photoresist mask used for making vias in low K carbon-doped silicon oxide dielectric material, and for removal of etch residues from formation of vias and removal of photoresist mask

FILING FEE	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT	<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time)
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